

TDDB Evaluation System AMM-1000



Precise data acquisition Endless pursuit for reliability The Oxide Film Property Evaluation System

As wafer size is enlarged for mass production of high-density, high-function LSIs, reliability evaluation of oxide film is on increasing demand, which is key for LSI reliability. ESPEC'S TDDB Evaluation System will play an indispensable role for analyzing failure caused by pressure resistivity of thin insulation oxide film and characteristics and flattening of oxide film, at wafer, glass substrate, and package level.



MEASUREMENT EVALUATION SYSTEMS

CONDUCTOR RESISTANCE EVALUATION SYSTEM

- THROUGH-HOLE CONDUCTOR EVALUATION SYSTEM
- SOLDER-JOINT CONTACT EVALUATION SYSTEM
- BGA, CSP SOLDER JOINT CONTACT EVALUATION SYSTEM
- CONNECTOR CONTACT RESISTANCE EVALUATION SYSTEM
- FPC LIFE EVALUATION SYSTEM
- OTHER INTERCONNECTION MATERIAL CONTACT EVALUATION SYSTEM

ION MIGRATION EVALUATION SYSTEM

INSULATION RESISTANCE EVALUATION SYSTEM

- CAPACITOR INSULATION RESISTANCE EVALUATION SYSTEM
- PCB, PWB INSULATION RESISTANCE EVALUATION SYSTEM
- INSULATION RESISTANCE EVALUATION SYSTEM FOR OTHER INSULATION MATERIAL
- LOW-K INSULATION CHARACTERISTIC EVALUATION SYSTEM

LEAK CURRENT MEASUREMENT SYSTEM

- CAPACITOR LEAK CURRENT MEASUREMENT SYSTEM
- FET LEAK CURRENT MEASUREMENT SYSTEM
- SEMICONDUCTOR REVERSE BIAS LEAK CURRENT MEASUREMENT SYSTEM
- CAPACITOR TEMPERATURE PROPERTY EVALUATION SYSTEM

LASER DIODE AGING SYSTEM

INTERCONNECTION MEASUREMENT EVALUATION SYSTEM

- CONNECTOR DISCONNECTION EVALUATION SYSTEM
- SOLDER-JOINT DISCONNECTION EVALUATION SYSTEM
 HARNESS CONTINUITY EVALUATION SYSTEM
- ELECTRONICS PARTS ELECTRIC PROPERTY AUTOMATIC EVALUATION SYSTEM
- TEMPERATURE COMPENSATED CRYSTAL OSCILLATOR TEMPERATURE PROPERTY TEST SYSTEM
- OPTICAL COMPONENT ENVIRONENTAL TEST SYSTEM

ELECTRO-MIGRATION EVALUATION SYSTEM

- LSI ELECTRO-MIGRATION EVALUATION SYSTEM
- GMR HEAD ELECTRO-MIGRATION EVALUATION SYSTEM
- GMR HEAD ELECTRO-MIGRATION RH EVALUATION SYSTEM
- HIGH FREQUENCY ELECTRO-MIGRATION EVALUATION SYSTEM
- WAFER LEVEL
- PACKAGE LEVEL

TDDB EVALUATION SYSTEM

- SEMICONDUCTOR PARAMETER AUTOMATIC EVALUATION SYSTEM
- FET(HOT-CARRIER) PROPERTY EVALUATION SYSTEM
- TRANSISTOR PROPERTY EVALUATION SYSTEM
- COMBINED ENVIRONMENTAL TESTING, MEASUREMENT & EVALUATION SYSTEM
- AUTOMATED RESONANCE POINT SEARCH & MEASUREMENT SYSTEM

Performance



Prober for LCD

APPLICATIONS

TDDB evaluation system

Package level Wafer level (for 8 inch wafer, 12 inch wafer)

FET(Individual transistor) property evaluation system

Package level Wafer level (for 8 inch wafer, 12 inch wafer)

Semiconductor, Liquid crystal glass substrate, etc..



Connection

System configuration to fit number of measurement

Equipped with DC Multi Source Measurement (MSM) on each channel, which enable monitoring and output of voltage and current. MSM consists of 4 channels per board. The basic 40-channel configuration stores up to 10 boards. The system can be upgraded according to measurement volume and condition up to 5 units (200 MSMs).

Precise current and voltage application measurement

Current at 9 ranges, measurement resolution of maximum current ±100mA, and minimum current ±1pA. Voltage at 2 ranges, resolution of maximum voltage ±50V and minimum voltage 1mV. Enables a wide range and precise application and measurement.

Measurement at minimum 10msec

Delivers high-speed measurement for multiple channels. Measures at top speed of 10 msec per 40 channels, while acquiring data.

Various evaluation items

The TDDB Evaluation System is configured for wafer level and liquid crystal glass substrate level, by effectively systemizing MSM. It also applies for requirements of QDB evaluation and TZDB evaluation, while FET property evaluation can also be realized by exchanging software.

Output by CSV file

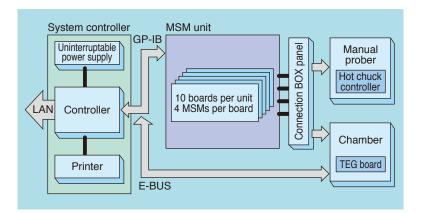
Automatic compilation of CSV file enable output by normal plotting. (Spread sheet software Microsoft EXCEL data can also be converted)

LAN compatible

Expansion to high-voltage load

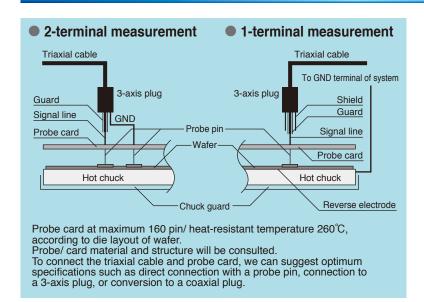
To upgrade the system, we provide MSM boards designed specifically for a maximum +100V high-voltage load.

SYSTEM BLOCK DIAGRAM



- Uninterruptable power supply Backup power supply for controller (Does not reset automatically when power restored)
- MSM unit Incorporates 40ch MSMs per unit (maximum 5 units)
- Connection BOX panel Can be set as panel for prober shield BOX.
- Triaxial cable Connects specimen and MSM to reduce noise level.
- Chamber
 Evaluation at package level of specimen, under high temperature, using the TEG board.
- E-BUS
 Temperature control, monitor, alarm control of chamber with a GP-IB adapter.

CONNECTION TO A PROBER



Prober

Type1

Wafer level prober

For both 5 inch type and 8 inch type Compatible with 300mm wafer type full automatic prober

Type2

Liquid crystal glass substrate (maximum 500×400mm)

Hot chuck
 Compatible prober :
 maximum 300°C for wafer level

maximum 150°C for liquid crystal glass substrate.

Probe card
 We offer optimum probe card to meet required
 specification and layout such as number of
 channels, pins and wafer size. Enables whole
 contact with a single shot.

SPECIFICATION

Model		AMM-1000		
Sofware		Windows® 2000		
Voltage/current application range		-50V to +50V/ -100mA to +100mA		
Resolution		1mV step/ 1pA step		
Voltage/current measurement range		-50V to +50V/ -100mA to +100mA		
No. of measurement channels		Standard 40ch. Max. installment 200ch		
No. of measurement channels Measurement sampling speed		Short mode: 0 to 100msec→10msec interval 100msec to 10sec→100msec interval Over 10sec→according to time table below Data acquisition without averaging Medium mode: 0 to 100msec→20msec interval 100msec to 10sec→100msec interval Over 10sec→according to time table below Averaging per 1 cycle Long mode: 0 to 10sec→100msec interval Over 10sec→according to time table below Averaging per 5 cycle Time table 10[sec] ~100[sec] 1[sec] × multiply by 1, 2, 5 or 10 100[sec] ~10000[sec] 100[sec] × multiply by 1, 2, 5 or 10 10000[sec] ~100000[sec] 1000[sec] × multiply by 1, 2, 5 or 10 10000[sec] ~100000[sec] 10000[sec] × multiply by 1, 2, 5 or 10 10000[sec] ~100000[sec] × multiply by 1, 2, 5 or 10		
External MSM	unit	650W×1300H×800Dmm		
dimension Syste	System controller	570W×1100H×900Dmm		
Doguired utility		100V AC±10% 50/60Hz 15A		
Required utility		100V AC±10% 50/60Hz 50A		

MSM Simplex Performance

Voltage range	Resolution	Accuracy	Max. current
±10V	1mV	±(0.2%+10mV)	100mA
±50V	10mV	±(0.2%+50mV)	TOOTTA

Current range	Resolution	Accuracy	Max. current
±100mA	100μA	\pm (0.5%+100 μ A+2 μ A×Vo)	
±10mA	10μA	\pm (0.5%+10 μ A+200nA \times Vo)	
±1mA	1μΑ	\pm (0.5%+1 μ A+20nA \times Vo)	
±100μA	100nA	±(0.5%+100nA+2nA×Vo)	
±10μA	10nA	±(1.0%+10nA+200pA×Vo)	50V
±1μ A	1nA	±(1.0%+1nA+20pA×Vo)	
±100nA	100pA	±(10%+100pA+2pA×Vo)	
±10nA	10pA	±(2.0%+10pA+200fA×Vo)	
±1nA	1pA	±(2.0%+1pA+20fA×Vo)	

Accuracy: \pm (set value or % of specified value) \pm (offset), Vo: output voltage (V)

Option

• Wafer prober (8 inch, 12 inch)

8 inch

Prober	Manual prober	750W×1500H× 800Dmm
external	Semi auto prober	1100W×1600H× 900Dmm
dimension	Full auto prober	1000W×1200H×1000Dmm
Temperature range	MAX +300°C Resolution 1°C step	
Required utility	200V AC±10% 50/60Hz 30A×1	

^{*}Please contact us for details of 12 inch prober.

- Prober for liquid crystal
- Prober card

*Utility for prober differs according to type of prober. We can coordinate your system accordingly.

• Chamber

Chamber external dimensiona	750W×1500H×800Dmm
Temperature range	MAX +250°C Resolution 1°C step
Required utility	200V AC±10% 50/60Hz 20A×1

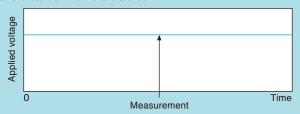
• Applied voltage, +100V Specification

EVALUATION PROCEDURES

Execute test by selecting from the following measurement mode library.

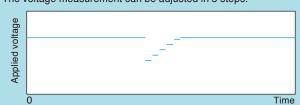
Fixed Voltage Measurement Mode

Measured with fixed voltage stress. The measurement current and breakdown time are stored.



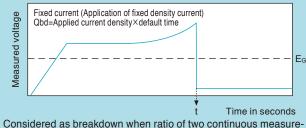
Soft Breakdown Mode

Measured by changing stress voltage and measurement voltage. The voltage measurement can be adjusted in 5 steps.



Current Stress Measurement

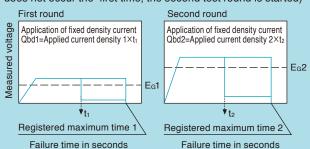
Voltage is measured by applying fixed current. The default time is recorded and stored.



Considered as breakdown when ratio of two continuous measurement value is above ∠EG electric field strength ratio.

Two-Step Current Stress Measurement

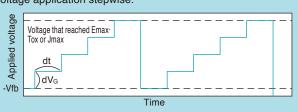
Different fixed current is applied two times (When breakdown does not occur the first time, the second test round is started)



Considered as breakdown when ratio of two continuous measurement value at both rounds is above ⊿EG electric field strength ratio for both the first and second rounds.

Step Voltage Measurement (I-V characteristics measurement, TZDB method)

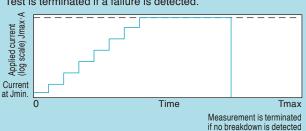
Measures the current at each voltage level while increasing voltage application stepwise.



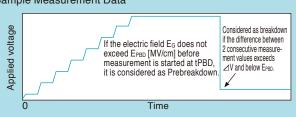
Step Current Measurement (TZDB)

Measures time dependent change of voltage while increasing current application stepwise.

Test is terminated if a failure is detected.



Sample Measurement Data



ESPEC CORP. http://www.espec.co.jp/english

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